IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Joseph M. Steigerwald

Serial No .:

10/722,801

Filed:

November 26, 2003

For:

Electrochemically Polishing Conductive

Films on Semiconductor Wafers

Art Unit:

2815

Examiner:

Sheila V. Clark

AF/IFW

Atty Docket: ITL.0947US

P15971

Assignee:

Intel Corporation

Mail Stop AF Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

REPLY TO FINAL REJECTION

Sir:

In response to the final rejection mailed April 19, 2005, please amend the abovereferenced patent application as follows:

Date of Deposit: May 4, 2005 I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, P.9. Box 1450,

Cynthia U. Hayden

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